L Number	Hits	Search Text	DB	Time stamp	- 4 - 2
_	8	118/719.ccls. and (chamber with pressure	USPAT;	2003/04/06 16	:16
		with higher with prevent)	US-PGPUB		
_	1	("20010040145").PN.	USPAT;	2003/02/26 10	:13
	!	,	US-PGPUB		
	3	(("5709785") or ("6251191") or	USPAT;	2003/04/04 16	:58
_	3			2003/04/04 10	
		("4576830")).PN.	US-PGPUB	0000 (04 (04 17	~ ~
-	1	("6358377").PN.	USPAT;	2003/04/04 17	: 00
			US-PGPUB	1	
-	l 0	6358377.URPN.	USPAT	2003/04/04 17	:00
_	lil	("6228439").PN.	USPAT;	2003/04/04 17	:02
	<u> </u>	( 0220433 )	US-PGPUB		
	, !	C000420 (IDDN)	USPAT	2003/04/04 17	• N 3
<del>-</del> .	1				
_	1	6228439.URPN.	USPAT	2003/04/04 17	
_	329	118/719.ccls. and (conveyor track rail)	USPAT;	2003/04/04 17	: 0 /
	1		US-PGPUB		
_	38	118/719.ccls. and (conveyor track rail)	USPAT;	2003/04/04 17	:07
		and cluster	US-PGPUB	,	
	۱ ،	6235634.URPN.	USPAT	2003/04/04 17	. 1 0
-	8		1		
_	124	414/\$.ccls. and (conveyor track rail) and	USPAT;	2003/04/04 17	: 25
		cluster and (rotat\$3)	US-PGPUB		
_	53	414/\$.ccls. and (conveyor track rail) and	USPAT;	2003/04/04 18	:36
		cluster and (rotat\$3) and (substrate water	US-PGPUB		
		semiconductor)	1		
	1		IICDAM	2003/04/04 17	. = 1
<del>-</del>	72	4643629.URPN.	USPAT		
-	72	4643629.URPN.	USPAT	2003/04/04 17	
_	28		USPAT	2003/04/04 18	
_	481	414/\$.ccls. and ((conveyor track rail)	USPAT;	2003/04/04 18	:36
	1	same (turntable))	US-PGPUB	1	
	12	414/\$.ccls. and ((conveyor track rail)	USPAT;	2003/04/04 18	. 5
-	12		1	2003/04/04 10	
	1	same (turntable with rotat\$3) same	US-PGPUB		
		(substrate wafer semiconductor))			
_	677	(414/749.1-749.6).CCLS.	USPAT;	2003/04/06 14	:52
	1	[ , , , , , , , , , , , , , , , , , , ,	US-PGPUB		
	55	(414/749.4).CCLS.	USPAT;	2003/04/06 15	:09
_	33	· / 111/113.1/.00113.	US-PGPUB	2000/04/00 13	
	I	1 4 1 1 1 1 1 1 1 1 1 1 1 1 1 1 1 1 1 1		10002/04/05 15	
-	279	(414/936).CCLS.	USPAT;	2003/04/06 15	: 5
		*	US-PGPUB	1	
-	72		USPAT	2003/04/06 15	
-	3548126	414/939.ccls. no ((414/936).CCLS.)	USPAT;	2003/04/06 15	:56
	1		US-PGPUB		
_	485	414/939.ccls.	USPAT;	2003/04/06 15	:50
_	403	414/939.6618.		2003/01/00 13	• •
		1111000	US-PGPUB	2002/04/05 15	
_	426	414/939.ccls. not ((414/936).CCLS.)	USPAT;	2003/04/06 15	: 5
			US-PGPUB		
_	426	414/939.ccls. not ((414/936).CCLS.)	USPAT;	2003/04/06 15	: 5
	1		US-PGPUB		
_	69	3874525.URPN.	USPAT	2003/04/06 16	: n
_			USPAT;	2003/04/06 17	
-	414			2003/04/06 1/	. 4
		substrate) with vertical\$3)	US-PGPUB	1 0005 12: 12:	
-	28		USPAT	2003/04/06 16	
-	62	4500407.URPN.	USPAT	2003/04/06 20	1:2
_	1	("5888303").PN.	USPAT;	2003/04/06 17	: 4
	1	1, 230000 /	US-PGPUB		-
	_	110/710 0010 003 (004040)		2003/04/06 17	
_	2		USPAT;	2003/04/00 1/	. 5
		vertical\$3 with (transfer\$3 transport\$3)	US-PGPUB		
		with chamber)			
_	91	118/719.ccls. and (vertical\$3 with	USPAT;	2003/04/06 17	:5
	1	(transfer\$3 transport\$3) with chamber)	US-PGPUB		
	900		USPAT;	2003/04/06 17	1.5
	802	110//30.0018.		2003/04/00 1/	٠.
-	i .		US-PGPUB	2003/04/06 18	٠. ٥
-				1 2003/07/06 19	( . 11
-	55	156/345.55.ccls.	USPAT;	2003/04/00 IC	, . U
-	55	156/345.55.ccls.	US-PGPUB		
-					
	55 125		US-PGPUB USPAT;	2003/04/06 18	
	125	156/345.55.ccls. 156/345.54.ccls.	US-PGPUB USPAT; US-PGPUB	2003/04/06 18	3:0
		156/345.55.ccls. 156/345.54.ccls. 414/\$.ccls. and (conveyor track rail) and	US-PGPUB USPAT; US-PGPUB USPAT;		3:0
	125 155	156/345.55.ccls. 156/345.54.ccls. 414/\$.ccls. and (conveyor track rail) and cluster	US-PGPUB USPAT; US-PGPUB USPAT; US-PGPUB	2003/04/06 18	3:0 3:0
	125	156/345.55.ccls. 156/345.54.ccls. 414/\$.ccls. and (conveyor track rail) and	US-PGPUB USPAT; US-PGPUB USPAT; US-PGPUB USPAT;	2003/04/06 18	3:0 3:0
	125 155	156/345.55.ccls. 156/345.54.ccls. 414/\$.ccls. and (conveyor track rail) and cluster	US-PGPUB USPAT; US-PGPUB USPAT; US-PGPUB USPAT;	2003/04/06 18	3:0
	125 155	156/345.55.ccls. 156/345.54.ccls.  414/\$.ccls. and (conveyor track rail) and cluster 118/\$.ccls. 156/3453\$.ccls. 414/\$.ccls. and ((vertical\$3 with (substrate wafer	US-PGPUB USPAT; US-PGPUB USPAT; US-PGPUB	2003/04/06 18	3:0
	125 155	156/345.55.ccls. 156/345.54.ccls.  414/\$.ccls. and (conveyor track rail) and cluster 118/\$.ccls. 156/3453\$.ccls. 414/\$.ccls.	US-PGPUB USPAT; US-PGPUB USPAT; US-PGPUB USPAT;	2003/04/06 18	3:0

-		(118/\$.ccls. 156/3453\$.ccls. 414/\$.ccls.) and ((vertical\$3 with (substrate wafer semiconductor) with (transfer\$3	USPAT; US-PGPUB	2003/04/06 19:10
		transport\$3)) same cluster)		
_	5	5738767.URPN.	USPAT	2003/04/06 19:12